

FORM PTO-1449 (Modified)		US DEPARTMENT OF COMMERCE		Docket No. 050623.245		Application No. 10/623.908	
US Patent and Trademark Office							
INFORMATION DISCLOSURE CITATION in an Application (Use several sheets if necessary)							
U.S. PATENT DOCUMENTS							
Examiner Initial	Ref. No.	Document Number	Date of Patent	Name	Class	Subclass	Filing Date if Appropriate
	A1						
U.S. PATENT APPLICATIONS							
Examiner Initial	Ref. No.	Document Number	Date of Patent	Name	Class	Subclass	Filing Date if Appropriate
	A2						
FOREIGN PATENT DOCUMENTS							
Examiner Initial	Ref. No.	Document Number	Date of Publication	Country	Class	Subclass	Translation Yes No
	B1	WO 2005/113856	12/1/05	WIPO			X
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, etc.)							
C1	Aluminium oxide, Wikipedia, the free encyclopedia, downloaded from http://en.wikipedia.org/wiki/Alumina , June 12, 2007, 5 pgs.						
C2	Ceramic, Wikipedia, the free encyclopedia, downloaded from http://en.wikipedia.org/wiki/Ceramic , June 12, 2007, 8 pgs.						
C3	"Ceramics-a.k.a. 'burnt stuff'- contain at least 1 metal oxide", CCMR-Ask A Scientist, downloaded from http://www.ccmr.cornell.edu/education/ask/index.html?quid=1088 , June 12, 2007, 2 pgs..						
C4	Chen, "New Coating Process Enables Higher-Efficiency Engines", Berkeley Lab Research News, 1996, 3 pgs.						
C5	Chen et al., "Al ₂ O ₃ - TiO ₂ composite oxide films on etched aluminum foil by hydrolysis precipitation and anodizing", J. Mater. Sci. 41, pp. 569-571 (2006).						
C6	Ciridon et al., "Plasma Deposition", Biomaterials Tutorial, Univ. of Washington Engineerrd Biomaterials, 2004, 3 pgs.						
C7	Holcombe Jr. et al., "Oxygen sensitive, refractory oxide composition", downloaded from http://www.patentdigi.com/liquid_crystal/oxygen_sensitive_refractory_oxide_composition , June 12, 2007, 7 pgs.						
C8	Kern et al., "Electrolytic Deposition of Valve Metal Oxide Thin Films as Interference Coatings on Biomedical Implants", EU Cells and Materials vol. 10, Suppl. 1, 2005, pg. 25.						
C9	"Plasma Processing and Low Energy Plasma Science" The National Academies Press, downloaded from http://books.nap.edu/openbook.php?record_id , June 12, 2007, 5 pgs.						
C10	Zhitomirsky, "Ceramic Films Using Cathodic Electrodeposition", downloaded from http://www.tms.org/pubs/journals/JOM/0001/Zhitomirsky/ , June 12, 2007, 11 pgs.						
C11	Wood et al., "Implantation and deposition of adherent metal-oxide ceramic", IEEE Xplore, downloaded from http://ieeexplore.ieee.org/xpl/freeabs_all.jsp?arnumber=533482 , June 12, 2007, 1 pg.						
EXAMINER				DATE CONSIDERED			
EXAMINER: Initial if references considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							